

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
Dong-ha SHIM) Group Art Unit: Unassigned
Application No.: New Application) Examiner: Unassigned
Filed: Herewith)
For: MEMS DEVICE HAVING)
FLEXURES WITH NON-LINEAR)
RESTORING FORCE)

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to examination on the merits, kindly amend the above-captioned application as follows:

IN THE TITLE:

Kindly replace the title with --MEMS DEVICE HAVING FLEXURES WITH
NON-LINEAR RESTORING FORCE--

IN THE SPECIFICATION:

Kindly add the following paragraph on page 1, after the title of the invention and before the "Background of the Invention," --Priority is claimed to Patent Application Number 2001-9955 filed in the Republic of Korea on February 27, 2001, herein incorporated by reference.--

IN THE CLAIMS:

Kindly replace claim 5 as follows:

5. (Amended) The MEMS device of claim 1, wherein the moveable element moves in a direction perpendicular to the plane of the substrate.

Kindly add new claims 6-8 as follows:

--6. (New) The MEMS device of claim 2, wherein the moveable element moves in a direction perpendicular to the plane of the substrate.

7. (New) The MEMS device of claim 3, wherein the moveable element moves in a direction perpendicular to the plane of the substrate.

8. (New) The MEMS device of claim 4, wherein the moveable element moves in a direction perpendicular to the plane of the substrate.--

REMARKS

Claim 5 has been amended and claims 6-8 have been added to remove multiple dependency from the claims. The priority document has been incorporated by reference and a minor typographical error has been corrected in the title. Favorable action on the merits is respectfully requested.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

By: 

Charles F. Wieland III
Registration No. 33,096

P.O. Box 1404
Alexandria, Virginia 22313-1404
(703) 836-6620

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Attachment to Preliminary Amendment

Marked-up copy of Claim 6

5. (Amended) The MEMS device of [any one of claims 1 through 4] claim 1,
wherein the moveable element moves in a direction perpendicular to the plane of the
substrate.

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